

- How do generator and modulator type sensors differ from each others? Explain shortly the following sensor phenomena including explanation for the physical origin of the signal:
 - piezoresistivity
 - photoconductivity
 - pyroelectricity
 - piezoelectricity.
- Why SiO_2 and Si_3N_4 layers are often needed in microsensors? How are these layers fabricated, and how does the processing method effect on their properties?
- Explain, what means magnetoresistivity? Is it possible to use magnetoresistive sensors to measure the magnetic field of Earth (flux density appr. $50 \mu\text{T}$)? How many sensors are needed and how should they be positioned to each others for an electric compass? Are some other sensors needed in that application?
- Describe the structure and manufacturing principle of a micromechanical silicon microphone.
- Explain the operational principle and measurement method of the accelerometer shown in Fig. 1. Derive equation which describes the relation between sensor output signal V_O and acceleration. What is the resonant frequency of the sensor, when the proof mass $m = 200 \mu\text{g}$ and spring constant of the cantilever $k = 3300 \text{ N/m}$? Draw a sketch for the frequency response of the sensor.
- Present an electric equivalent circuit for a piezoelectric force sensor realized by using a quartz crystal. What is the time constant of the sensor? The arising voltage is measured from the crystal by using an amplifier, whose input resistance is $100 \text{ M}\Omega$. What is the lower cut-off frequency of the measurement system (sensor + amplifier)? Relative permittivity of quartz is $\epsilon_r = 4.5$, surface area and thickness of the crystal sensor are $A = 1 \text{ cm}^2$ and $d = 0.5 \text{ mm}$, respectively. Piezoelectric material constant and resistivity of quartz are $d_{33} = -2.3 \cdot 10^{-12} \text{ CN}^{-1}$ and $\rho = 7.5 \cdot 10^{17} \Omega\text{m}$, respectively. Permittivity of vacuum is $\epsilon_0 = 8.85 \cdot 10^{-12} \text{ Fm}^{-1}$.

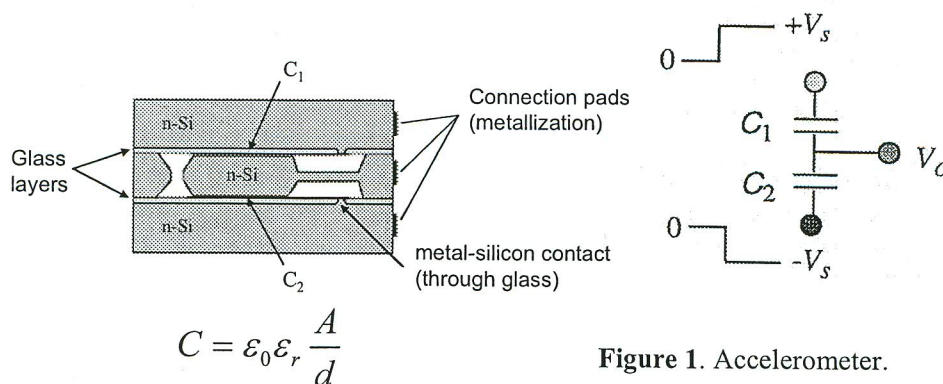


Figure 1. Accelerometer.